

BSIM4.5.0 Enhancements

Xuemei (Jane) Xi, Mohan Dunga, Ali M. Niknejad,
Chenming Hu

Department of Electrical Engineering and Computer Sciences,
University of California, Berkeley
JaneXi@eecs.Berkeley.EDU

June 24, 2005

BSIM4.5.0 New Features

- ❑ A mobility model which accounts for Coulomb scattering effect as well as the channel length dependence of mobility due to heavy halo-doping
- ❑ A scalable substrate resistance model ($r_{bodyMod} = 2$) that is scalable with channel length, channel width and number of fingers
- ❑ Gate resistance parameters XGW , $NGCON$ that can now be specified as instance parameters(XGL still model parameter)
- ❑ Additional temperature dependence of model parameters $VOFF$, $VFBSDOFF$
- ❑ Enhanced $tempMod = 2$, where $V_{th}(DITS)$ and gate tunneling models are functions of nominal temperature and the temperature dependence of zero-bias flat-band voltage is added
- ❑ A new instance parameter $DELVTO$ that may be used to represent threshold voltage variation
- ❑ A new well-proximity effect model developed by CMC companies
- ❑ I_{gc} V_{bs} dependence improvement with the full BSIM4 V_{th} model implemented

Mobility Model for BSIM4.5.0

Mobility Coulomb Scattering Model and L_{eff} dependence

- mobMod = 0

$$m_{eff} = \frac{U0 \cdot f(L_{eff})}{1 + \left(UA + UC V_{bseff} \right) \left(\frac{V_{gsteff} + 2V_{th}}{TOXE} \right) + UB \left(\frac{V_{gsteff} + 2V_{th}}{TOXE} \right)^2 + UD \left(\frac{V_{th} \cdot TOXE}{V_{gsteff} + 2V_{th}} \right)^2}$$

- mobMod = 1

$$m_{eff} = \frac{U0 \cdot f(L_{eff})}{1 + \left[UA \left(\frac{V_{gsteff} + 2V_{th}}{TOXE} \right) + UB \left(\frac{V_{gsteff} + 2V_{th}}{TOXE} \right)^2 \right] (1 + UC \cdot V_{bseff}) + UD \left(\frac{V_{th} \cdot TOXE}{V_{gsteff} + 2V_{th}} \right)^2}$$

- mobMod = 2

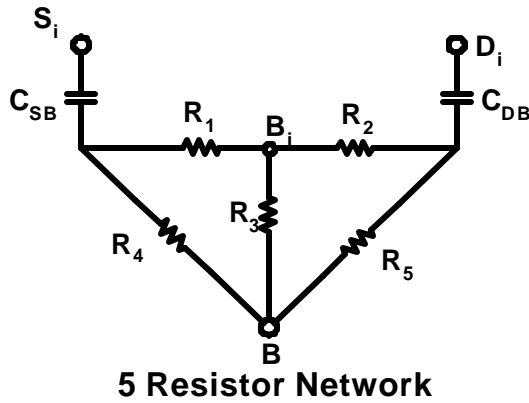
$$m_{eff} = \frac{U0 \cdot f(L_{eff})}{1 + \left(UA + UC \cdot V_{bseff} \right) \left(\frac{V_{gsteff} + C_0 \cdot (V_{th0} - V_{FB} - F_s)}{TOXE} \right) + UD \left(\frac{V_{th} \cdot TOXE}{V_{gsteff} + 2V_{th}} \right)^2}$$

Where: $f(L_{eff}) = 1 - UP \cdot e^{-L_{eff}/LP}$

The model is backward compatible with UP=0.0, UD=0.0

Scalable Substrate Resistance Model

$$R_X = R_{X_HORI} \parallel R_{X_VERT} \quad \text{where} \quad R_{X_H}(V) = R_0 L^a W^\beta NF^?$$



	HORIZONTAL CONTACT				VERTICAL CONTACT			
	R_0	a	b	g	R_0	a	b	g
R_1	1	2	3	4	NR	NR	NR	NR
R_2	1/5	2/6	3/7	4/8	NR	NR	NR	NR
R_3	5/9	6/10	7/11	8/12	9/13	10/14	11/15	12/16
R_4	13/17	14/18	15/19	16/20	17/21	18/22	19/23	20/24
R_5	13/25	14/18	15/19	16/20	17/26	18/22	19/23	20/24

- R_1, R_2 need not differentiate contact arrangements.
- R_4 and R_5 expected to have similar scaling laws.

Temperature Dependence for V_{OFF}, V_{FBSDOFF}

$$V_{OFF}(T) = V_{OFF}(T_{NOM}) \cdot [1 + TV_{OFF} \cdot (T - T_{NOM})]$$

$$V_{FBSDOFF}(T) = V_{FBSDOFF}(T_{NOM}) \\ \cdot [1 + TV_{FBSDOFF} \cdot (T - T_{NOM})]$$

New Temperature Mode (TempMod = 2)

Share the same temperature equations as for TempMod=1

AND:

From:

$$\Delta V_{th}(DITS) = -n v_t \cdot \ln \left(\frac{L_{eff}}{L_{eff} + DVTP0 \cdot (1 + e^{-DVTP1 V_{ds}})} \right)$$

To:

$$\Delta V_{th}(DITS) = -n v_{tnom} \cdot \ln \left(\frac{L_{eff}}{L_{eff} + DVTP0 \cdot (1 + e^{-DVTP1 V_{ds}})} \right)$$

Vfbzb(T)

$$V_{fbzb}(T) = V_{fbzb}(TNOM) - K T1 \times \frac{T}{TNOM} - \frac{1}{\theta}$$

Igate(T)

T is replaced by TNOM

DELVTO: an Instance Parameter

if v_{th0} is given:

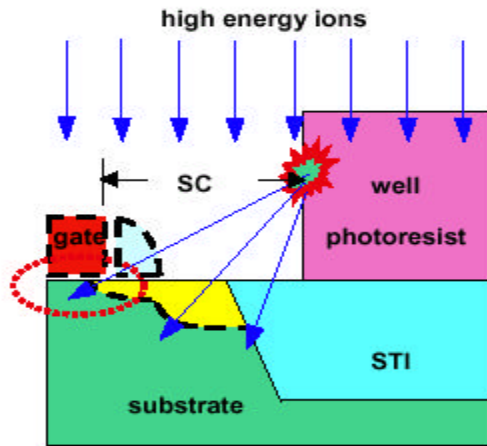
$$V_{th0} = V_{th0} + DELVTO;$$

if v_{th0} is not given,

$$V_{fb} = V_{fb} + DELVTO;$$

$$V_{th0} = V_{fb} + \phi + k_1 * \sqrt{k_1}$$

Well-Proximity Effect Modeling



Instance parameters: SCA, SCB, SCC, SC

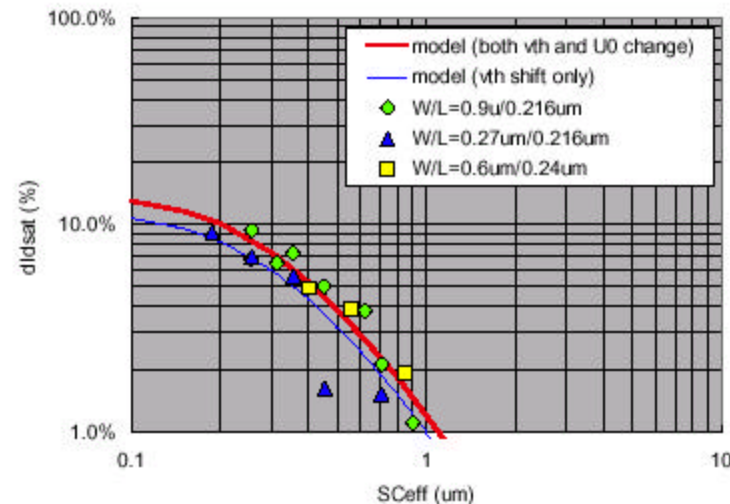
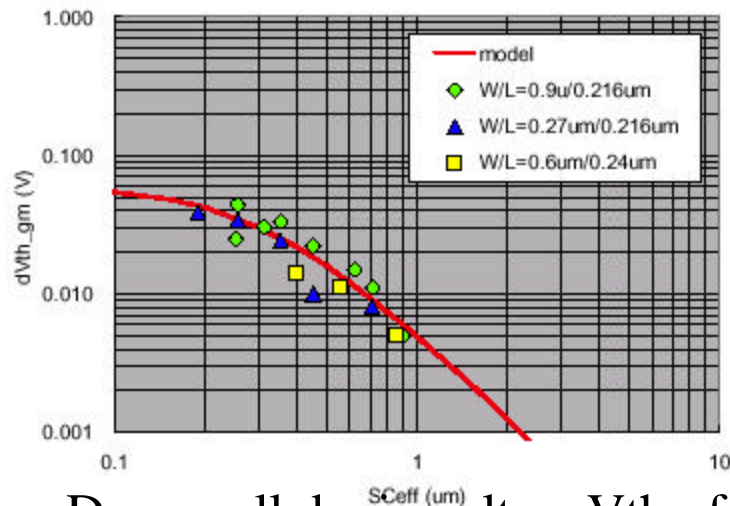
Model parameters: WEB, WEC, KVTH0WE, K2WE, KU0WE, SCREF, WPEMOD

Model equations:

$$V_{th0} = V_{th0_{org}} + KVTH0WE \times (SCA + WEB \times SCB + WEC \times SCC)$$

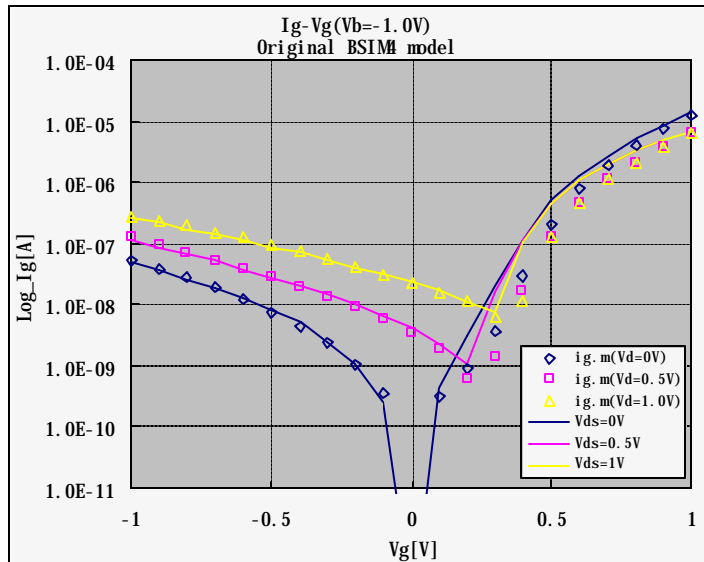
$$K2 = K2_{org} + K2WE \times (SCA + WEB \times SCB + WEC \times SCC)$$

$$m_{eff} = m_{eff,org} \times (1 + KU0WE \times (SCA + WEB \times SCB + WEC \times SCC))$$

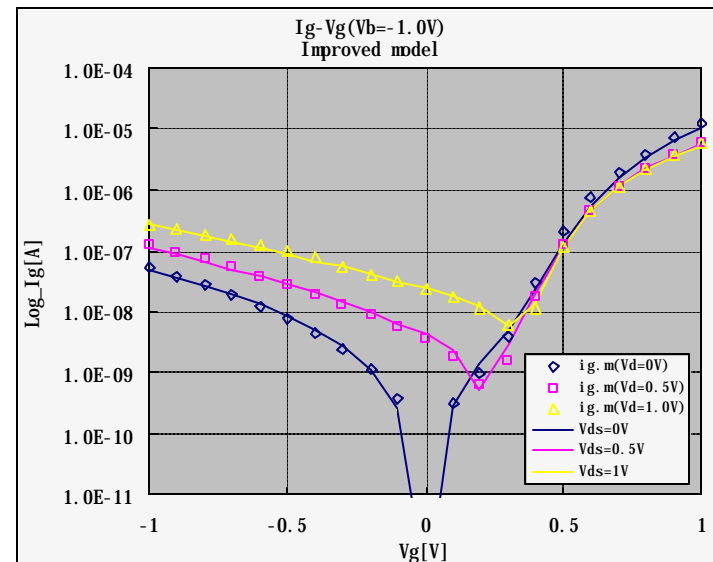


- Deep well doping alters V_{th} of devices near the mask edge: $V_{th}(SC)$
- CMC well-proximity effect model is able to capture the distance effect

Gate Current Vbs Dependence



Original Igc Model



Improved Igc model

$$I_{gc0} = W_{eff} L_{eff} \times A \times T_{oxRatio} \times V_{gse} \times V_{aux} \times \exp \left[-B \times TOXE \left(AIGC - BIGC \times V_{oxdepinv} \right) \times \left(1 + CIGC \times V_{oxdepinv} \right) \right]$$

$$\text{IGCMOD}=1 \quad V_{aux} = NIGC \times v_t \times \log \left(1 + \exp \left(\frac{V_{gse} - V_{TH0}}{NIGC \times v_t} \right) \right)$$

$$\text{IGCMOD}=2 \quad V_{aux} = NIGC \times v_t \times \log \left(1 + \exp \left(\frac{V_{gse} - V_{TH_bsim4}}{NIGC \times v_t} \right) \right)$$

Was physically derived !

- Implementing full BSIM4 Vth model into Igc enables the accurate prediction of Igc Vbs dependence.